

Thin film piezoelectric MEMS (Micro Electro Mechanical System) devices

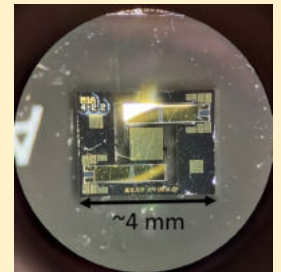
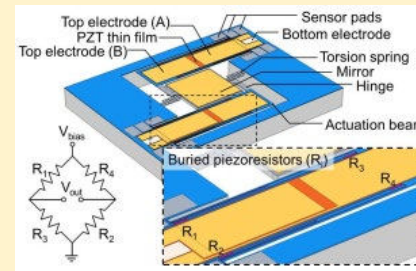


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The MEMS technology is key for next generation Society. Piezoelectric devices are fast, small and ultra-low power.

In recent years, piezoelectric MEMS devices are being developed for micromirrors (LiDAR, AR/VR, projection), ultrasonic transducers (biomedical use, HMI) and others.



Piezoelectric MEMS micromirror



Piezoelectric MEMS varifocal lens